INFORMATION DISCLOSURE STATEMENT				Atty Docket: 02GR128554494 Serial No.: Not Yet Assigned Applicant: BOUCHE ET AL. Filing Date: Herewith Group:					
U.S. PATENT DOCUMENTS									
Examiner Initials		Document Number	Date		Name		Class	Sub Class	Filing Date
	AA								
	AB								
	AC								
	AD								
	AE						,	_	
	AF							<u> </u>	
	AG								
	AH								_
: 	Al								
	AJ								
FOREIGN PATENT DOCUMENTS									
		Document Number	Date		Country		lass	Sub Class	Translation
116	AK	0907211	4/7/99	EP		H01L35		22	
	AL	01/29529	4/26/01	wo		н	01L21	302	
No	AM	1096259	5/2/01	EP		G	01P15	08	
	AN								
OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)									
Vlo	AO	Xiao et al., Silicon/Glass Wafer-to-Wafer Bonding with Ti/Ni Intermediate Bonding, Sensors and Actuators A, Elsevier Sequoia S.A., Lausanne, CH, Vol. 71, No. 1-2, November 1, 1998, Pages 123-126, XP004140083							
Vlo Llo	AP	Dehé et al., III-V Compound Semiconductor Micromachined Actuators for Long Resonator Tunable Fabry – Pérot Detectors, Sensors and Actuators A, Elsevier Sequoia S.A., Lausanne, CH, Vol. 68, No. 1-3, June 15, 1998, Pages 365-371, XP004139861							
	AQ								
EXAMINER:					DATE CONSIDERED: 2/25/16				

EXAMINER: Initial if reference consider d, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.